

Amendments to the Claims:

The listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

Claim 1. (Currently amended) A supply system of a compound for chemical vapor deposition, comprising:

an order-processing device for receiving a request for shipment of a compound for chemical vapor deposition from a customer, and for performing shipment processing;

an inventory database for storing an amount of shippable compound;

analyzing means having analysis information output means capable of analyzing a spent compound that is returned from the customer, and outputting, as analysis information, at least a weight of an unreacted compound in the spent compound;

regenerating means having regeneration information output means for separating the unreacted compound from the spent compound and refining the separated unreacted compound, and for outputting, as regeneration information, at least an amount of regenerated compound;

a stock-material information database for storing shipment information of the spent compound ~~at the time of initial shipment~~ that is regenerated by the supply system; and

a charging-processing device for performing price charging-processing for a regenerating cost for the customer,

wherein when a shipment request comes from the customer, the order-processing device judges whether shipment is possible by comparing the amount of shippable compound that is stored in the inventory database with an order amount of the customer, and performs shipment processing if the shipment is possible, and

after a the spent compound is returned from the customer, the charging-processing device calculates an amount of compound consumed by the customer based on the analysis information that is output from the analysis information output means and performs charging-processing for

the customer, and the inventory database extracts an amount of regenerated compound from the regeneration information that is output from the regeneration information output means and stores the amount of regenerated compound as an amount of shippable compound.

Claim 2. (Previously Presented) The supply system of a compound for chemical vapor deposition according to claim 1,

wherein the analysis information includes a density and composition as well as the weight of the unreacted compound in the spent compound.

Claim 3. (Previously Presented) The supply system of a compound for chemical vapor deposition according to claim 1, wherein the regeneration information includes purity and composition of the regenerated compound.

Claim 4. (Previously Presented) The supply system of a compound for chemical vapor deposition according to claim 1, wherein the shipment information includes purity and composition of a compound at the time of shipment.

Claim 5. (Previously Presented) The supply system of a compound for chemical vapor deposition according to claim 1, wherein the stock-material information database also stores the analysis information and the regeneration information.

Claim 6. (Previously Presented) The supply system of a compound for chemical vapor deposition according to claim 1, wherein the order-processing device, the inventory database, the analyzing means, the regenerating means, the charging-processing device, and the stock-material information database are connected to each other by a network.

Claim 7. (Withdrawn) A supply system of a compound for chemical vapor deposition, comprising:

an order-processing device for receiving a regeneration request from a customer;

regenerating means having regeneration information output means for separating an unreacted compound from a spent compound returned from the customer and refining the separated unreacted compound, and for outputting, as regeneration information, at least a weight of a regenerated compound;

a regeneration cost database in which a regeneration cost per unit weight corresponding to a kind of the spent compound returned from the customer is recorded; and

a charging-processing device for performing charging-processing for a regenerating cost for the customer,

wherein the charging-processing device calculates a regeneration cost based on the regeneration information that is output from the regenerating means and the regeneration cost database, and performs charging-processing for the customer.

Claim 8. (Withdrawn) The supply system of a compound for chemical vapor deposition according to claim 7,

wherein the regeneration information further includes purity and composition of the regenerated compound.

Claim 9. (Withdrawn) The supply system of a compound for chemical vapor deposition according to claim 7, wherein the order-processing device, the regenerating means, the charging-processing device, and the regeneration cost database are connected to each other by a network.

Claim 10. (Withdrawn) The supply system of a compound for chemical vapor deposition according to claim 7, further comprising analyzing means having analysis information output

means capable of analyzing the spent compound that is returned from the customer, and outputting, as analysis information, at least a weight of an unreacted compound in the spent compound.

Claim 11. (Withdrawn) The supply system of a compound for chemical vapor deposition according to claim 7, wherein the analysis information includes at least one of the weight, a density, and composition of the unreacted compound in the spent compound.

Claim 12. (Withdrawn) The supply system of a compound for chemical vapor deposition according to claim 10, wherein the order-processing device, the regenerating means, the charging-processing device, the regeneration cost database, and the analyzing means are connected to each other by a network.

Claim 13. (Withdrawn) A thin-film manufacturing system comprising: a compound supply section comprising a supply system of a compound for chemical vapor deposition according to claim 1; and a thin-film manufacturing section for manufacturing a thin film using a compound that is supplied from the supply system, comprising: a thin-film manufacturing apparatus; recovering means for recovering a spent compound that is discharged from the thin-film manufacturing apparatus; a storage device for storing an amount of spent compound recovered by the recovering means; and ordering-processing device for performing processing of ordering a new compound or processing of issuing request for regeneration of the recovered spent compound, wherein the order-processing device of the compound supply section and the ordering-processing device of the thin-film manufacturing section are connected to each other by a network.